

Aqua EP

“WET-EP” TYPE POU ABATEMENT

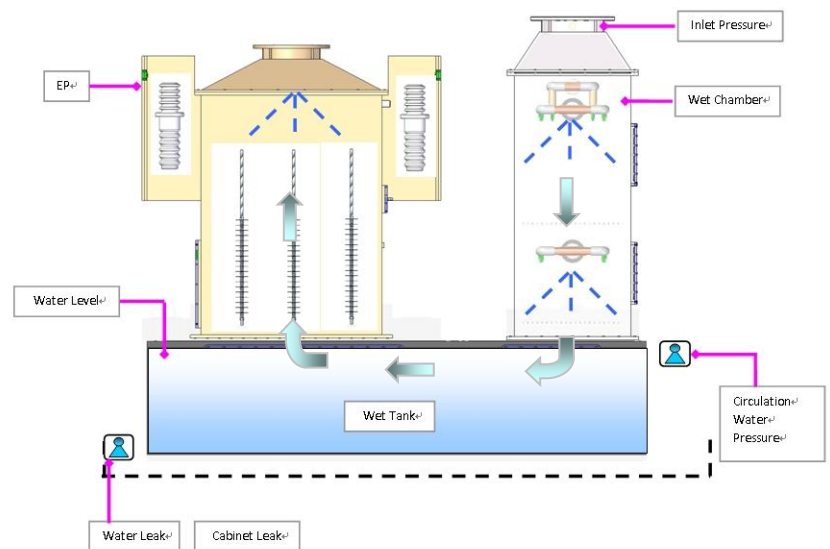
Exhaust solution for high-volume semiconductor manufacturing



Benefits

- > High abatement efficiency (white smoke elimination)
- > Acid and alkali gas scrubbing
- > Removal of fine particulate byproducts such as NH₄Cl
- > Lower infrastructure cost option compared to adding segregated exhaust
- > HVM (high volume manufacturing) proven

System Specifications



Applications

- > Semiconductor and display processes
 - o Mixed acid and alkali gas effluent
 - o Wet bench exhaust treatment
 - o Fine particulate removal

Features

- > Packed bed wet scrubbing stage
- > Fog nozzle wetting stage
- > Electric precipitator
- > Precipitator auto rinse
- > Purge blower for E/P system high voltage contact insulation enclosure
- > Diaphragm pump drain standard / gravity drain option
- > 5 HP induction fan option

- Total System Capacity: **50 m³ / minute**
- Per Inlet Capacity: **50 m³ / minute**
- Process Inlets: **VP 300 flange single entry**
- MTBF: **> 6,000 hours**
- MTRR: **< 1 hour**
- MTTP: **< 4 hour**

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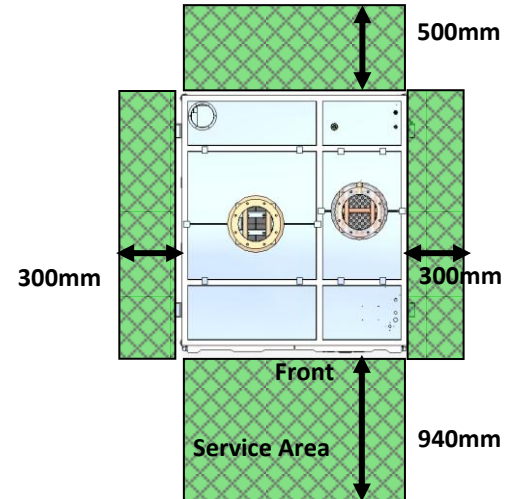


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Dimensions and Weight

	Aqua EP
Dimension (W x D x H in mm)	1600 x 1800 x 1850
Weight (kg)	950



Utilities

Item	Type	Typical Usage	Connection Type	
			Aqua EP	
Electricity	208VAC 3 Phase	5 KW (including ID fan)	30A service	
CDA	5 ~ 6.5 kg/cm ²	200 LPM	3/8" SS compression	
City Water	3 ~ 6 kg/cm ²	5 L/min	1/2" SS compression	
Drain Water	Acid Drain	5 L/min	Pump : 15A PVC union	Natural : 50A PVC union
Gas Exhaust	-50 ~ -80 mmH2O	50 m ³ /min	VP 300 Flange	
Cabinet Exhaust	-30 ~ -60 mmH2O	4.5 m ³ /min	MF100 Flange	

Environment

- Clean and dry environment
- Temperature: 5 ~ 27 °C
- Relative Humidity: < 55%

Abatement Noise Level

- Normal operation at ≤80 dB(A)